

EL 844051780

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09,388,826
Filing Date September 1, 1999
Inventor Weimin Li, et al.
Assignee Micron Technology, Inc.
Group Art Unit 2813
Examiner E. Kielin
Attorney's Docket No. MI22-1208
Title: Low k Interlevel Electric Layer Fabrication Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56.
Copies of the cited prior art references are attached. No admission is made regarding
whether the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,

Date:

Sep 25, 2001

By:

Bernard Berman

Bernard Berman, Reg. No. 37,279
WELLS, ST. JOHN, ROBERTS,
GREGORY & MATKIN P.S.
601 W. First Avenue, Suite 1300
Spokane, WA 99201-3828
(509) 624-4276

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